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CLAIMS

- 1. A substrate for use in a perpendicular magnetic recording medium, comprising a blank substrate and a film of phosphorus- or boron-containing cobalt alloy formed on the blank substrate by electroless plating, the electroless plated film of the cobalt alloy having surface roughness Ra in the range of 0.05 nm to 1 nm.
- 2. The substrate for use in a perpendicular magnetic recording medium according to Claim 1, wherein a number of defects occurring on a surface of the electroless plated film of the cobalt alloy and measuring 0.1 μm or more in diameter and 7 nm or more in depth is less than 5 per surface.
- 3. The substrate for use in a perpendicular magnetic recording medium according to claim 1, wherein a number of projections occurring on the surface of the electroless plated film of the cobalt alloy and measuring 0.1 µm or more in diameter and 7 nm or more in height is less than 5 per surface.
- 4. The substrate for use in a perpendicular magnetic recording medium according to any one of claims 1 to 3, wherein the electroless plated film of the cobalt alloy has a phosphorus content in the range of 1 mass% to 30 mass%.
- 5. The substrate for use in a perpendicular magnetic recording medium according to any one of claims 1 to 3, wherein the electroless plated film of the cobalt alloy has a boron content in the range of 0.1 mass% to 10 mass%.
- 6. The substrate for use in a perpendicular magnetic recording medium according to any one of claims 1 to 5, wherein the electroless plated film of the cobalt alloy has a thickness in the range of 0.1 μ m to 5 μ m.

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- 7. A method for the production of a substrate for use in a perpendicular magnetic recording medium, comprising a step of forming on a blank substrate a film of phosphorus- or boron-containing cobalt alloy by electroless plating and a step of polishing a surface resulting from the step of forming the film by the plating.
- 8. The method for the production of a substrate for use in a perpendicular magnetic recording medium according to claim 7, wherein the polishing step removes the electroless plated film of the cobalt alloy in a depth in the range of 0.15 μ m to 10 μ m and thins the electroless plated film of the cobalt alloy to a thickness in the range of 0.1 μ m to 5 μ m.
- 9. The method for the production of a substrate for use in a perpendicular magnetic recording medium according to claim 7 or 8, wherein the polishing step uses polishing liquid containing water and abrasive grains and further contains at least one member selected from the group consisting of an oxidizing agent, a chelating agent and a pH-adjusting agent.
- 10. The method for the production of a substrate for use in a perpendicular magnetic recording medium according to claim 9, wherein the polishing liquid has a pH value in the range of 3 to 9.5.
- 11. The method for the production of a substrate for use in a perpendicular magnetic recording medium according to claim 9 or 10, wherein the abrasive grains contained in the polishing liquid have a concentration in the range of 1 mass% to 30 mass%.
- 12. The method for the production of a substrate for use in a perpendicular magnetic recording medium according to any one of claims 9 to 11, wherein the abrasive grains contained in the polishing liquid are SiO₂ grains having an average particle diameter (D50) of 20 nm or less.

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- 13. The method for the production of a substrate for use in a perpendicular magnetic recording medium according to any one of claims 9 to 12, wherein the oxidizing agent contained in the polishing liquid is hydrogen peroxide.
- 14. The method for the production of a substrate for use in a perpendicular magnetic recording medium according to any one of claims 9 to 13, wherein the chelating agent contained in the polishing liquid contains at least one compound selected from the group consisting of EDTA, citric acid and succinic acid.
- 15. The method for the production of a substrate for use in a perpendicular magnetic recording medium according to any one of claims 9 to 14, wherein the pH-adjusting agent contained in the polishing liquid contains at least one member selected from the group consisting of aqueous ammonia, water-soluble organic acid and salts thereof.